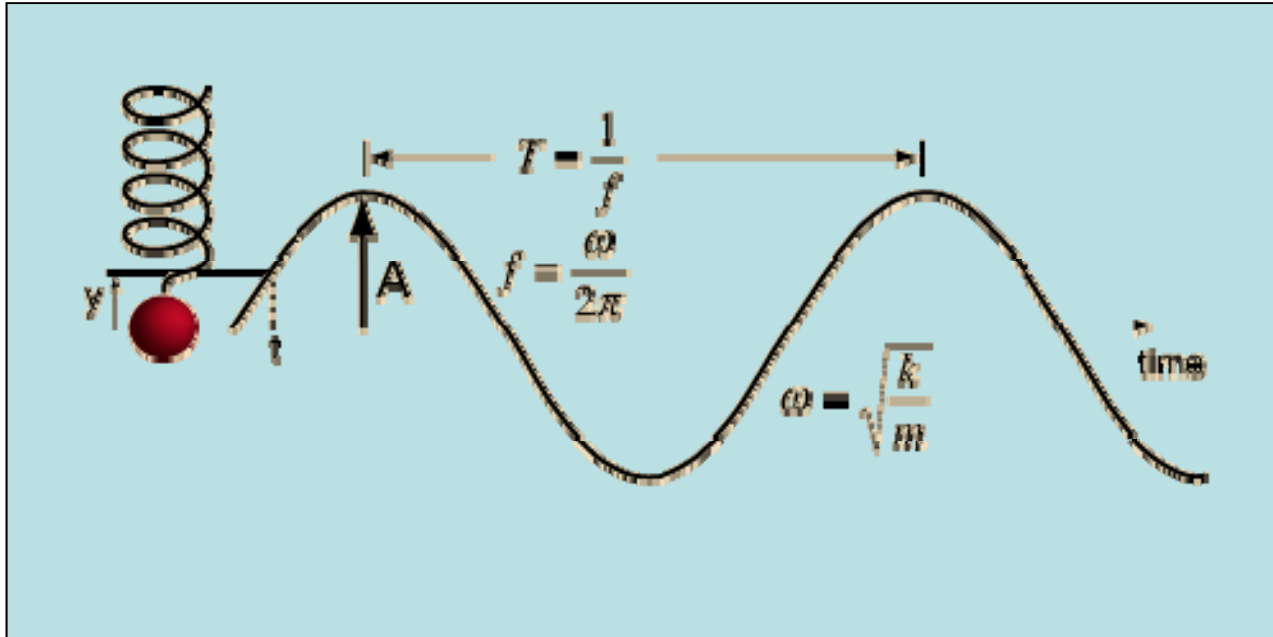


Lecture 5

Mechanical biosensors.
Microcantilevers. Thermal sensors.

Mechanical Mass Sensitive Sensors

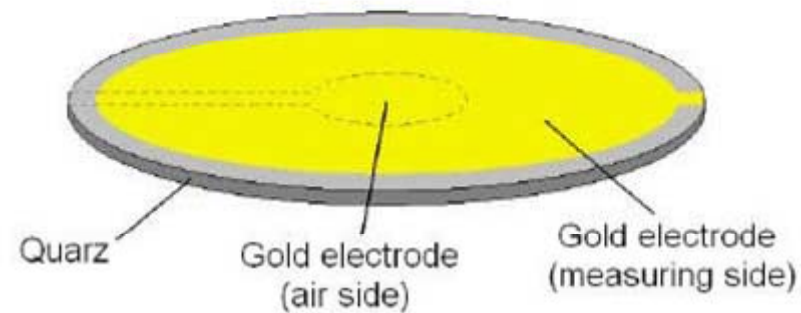


- Mechanical shift of a resonance can be used for detection of mass change (due to adsorption or chemical reaction)

Mechanical Mass Sensitive Sensors



Quartz crystal - The heart of the QCM



- Sauerbrey equation:

$$\Delta f = -[2 \times f_0^2 \times \Delta m] / [A \times (\rho_q \mu_q)^{1/2}], \text{ where}$$

Δf = measured frequency shift,

f_0 = resonant frequency of the fundamental mode of the crystal,

Δm = mass change per unit area (g/cm^2),

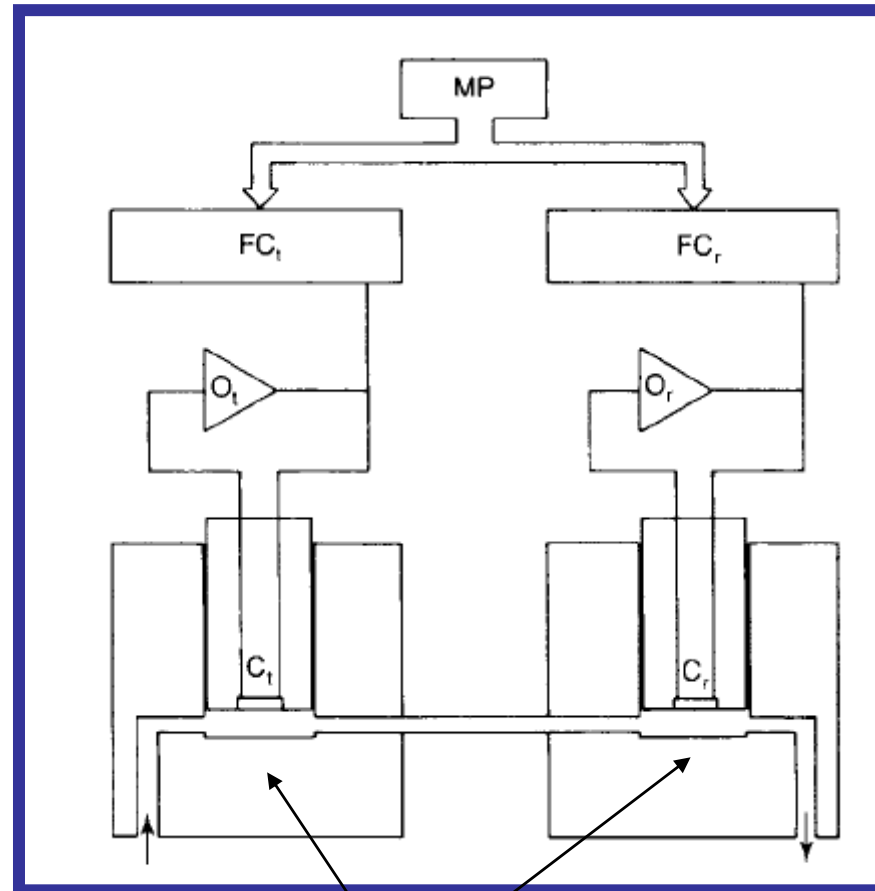
A = piezo-electrically active area,

ρ_q = density of quartz, $2.648 \text{ g}/\text{cm}^3$,

μ_q = shear modulus of quartz, $2.947 \times 10^{11} \text{ g}/\text{cm} \times \text{s}^2$.

$$\Delta f = -2.3 \times 10^6 f^2 \Delta m / A$$

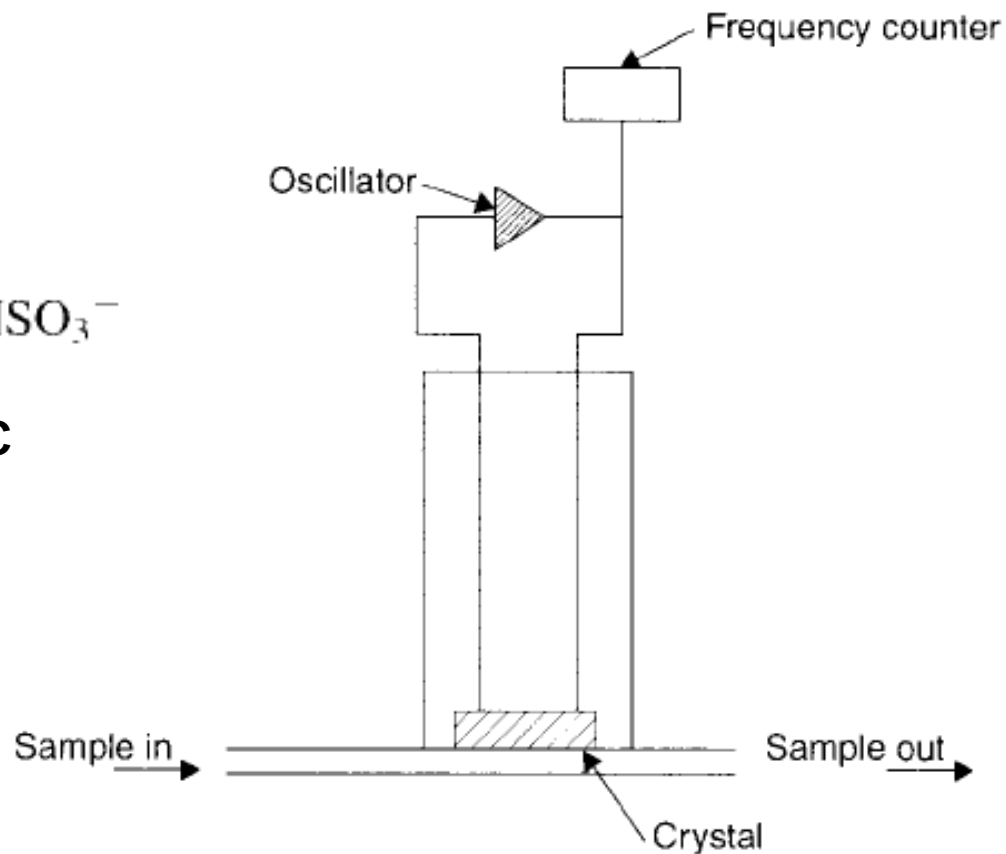
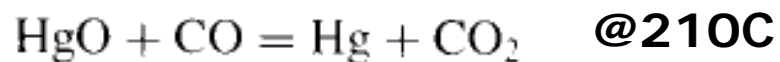
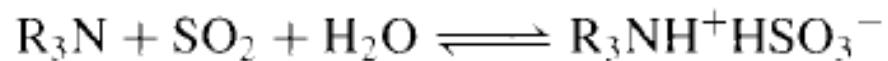
Quartz Crystal Microbalance



differential signal between two cells
is measured

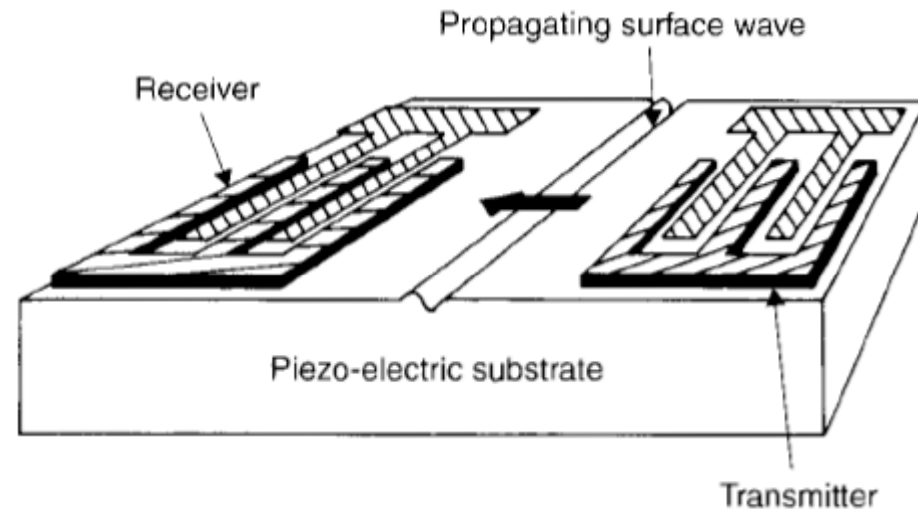
Mechanical Mass Sensitive Sensors

- Gas-Sensor Applications



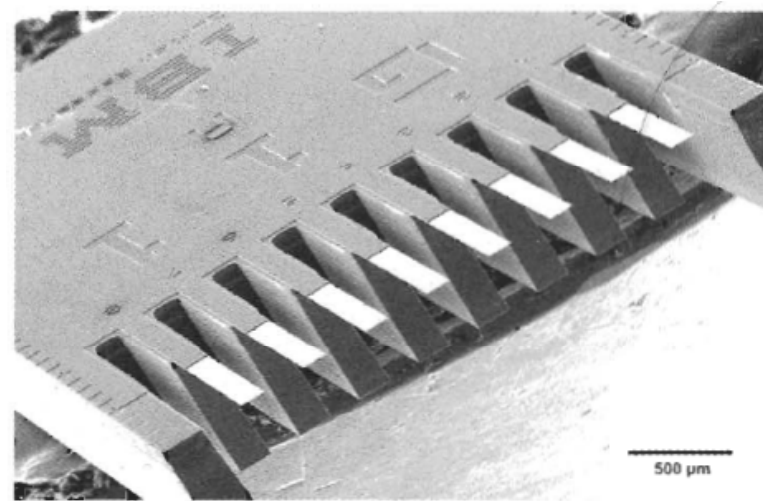
Mechanical Mass Sensitive Sensors

- Surface Acoustic Waves



Cantilever-based sensing

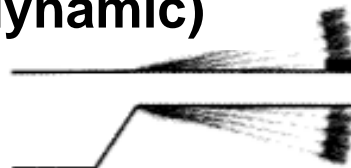
- label-free measurements
- low fabrication costs, mass production possible
- high sensitivity



surface stress sensor



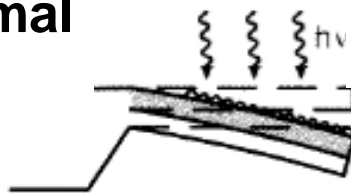
mass sensor (dynamic)



Heat sensor



Photothermal sensor



Electrostatic sensor

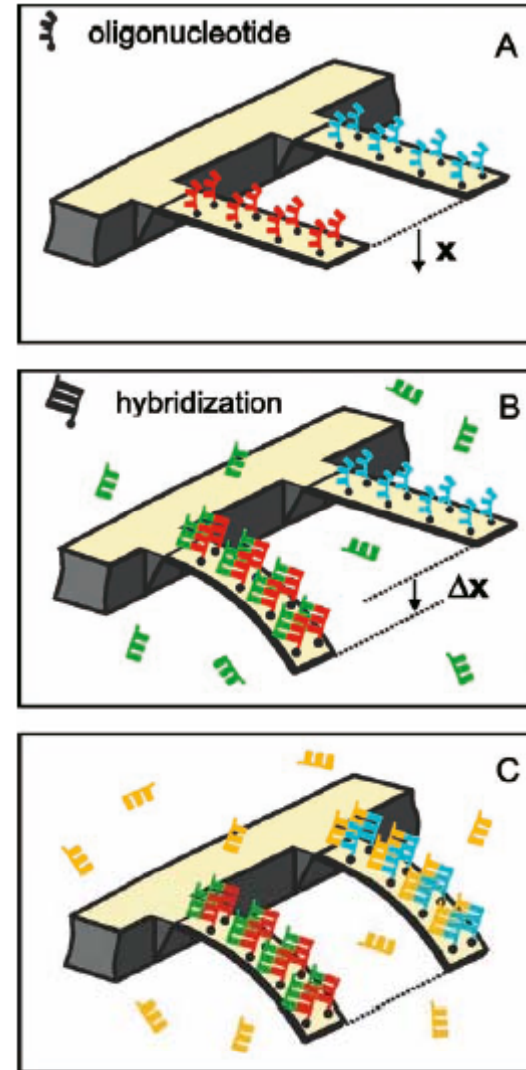


Magnetic sensor



Cantilever-based biosensing

- static bending
- frequency change
- reference is required



Static mode sensing

- Static mode:
 - essential to functionalize one side of the cantilever **only**.
 - cantilever deformation is related to the interaction forces (binding to the receptor and the surface as well as intermolecular interaction incl.
 - electrostatic,
 - van der Waals,
 - changes in surface hydrophobicity
 - conformational changes of the adsorbed molecules

Stoney formula (1909):

$$\Delta\sigma_1 - \Delta\sigma_2 = \frac{Eh^2}{3L^2(1-\nu)} \Delta z$$

$(\Delta\sigma_1 - \Delta\sigma_2)$ – surface stress change between top and bottom,

E – Young's modulus

L and h - length and thickness of the cantilever

ν – Poisson module

Δz – cantilever free end displacement

Dynamic mode sensing

- Measures the total mass adsorbed
- Can be used with both sides functionalization
- Attogram sensitivities can be achieved
- Main difficulties related to the energy dissipation and low Q-factor in fluids

$$\Delta f = \sqrt{3} \frac{f_0}{Q}$$

← operating frequency

← quality factor

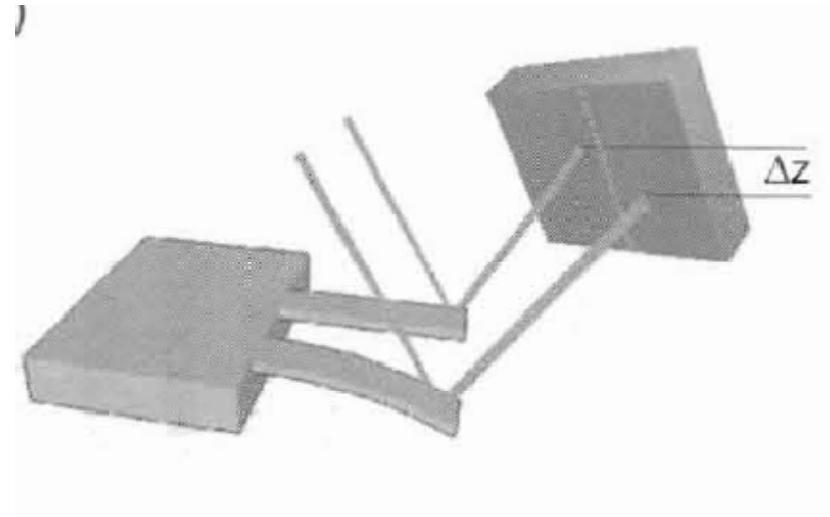
- using high eigen frequency cantilevers
- performing measurements in air after functionalization
- using higher harmonics
- using external feedback (Q-control)

Detection Techniques

Most used technique!

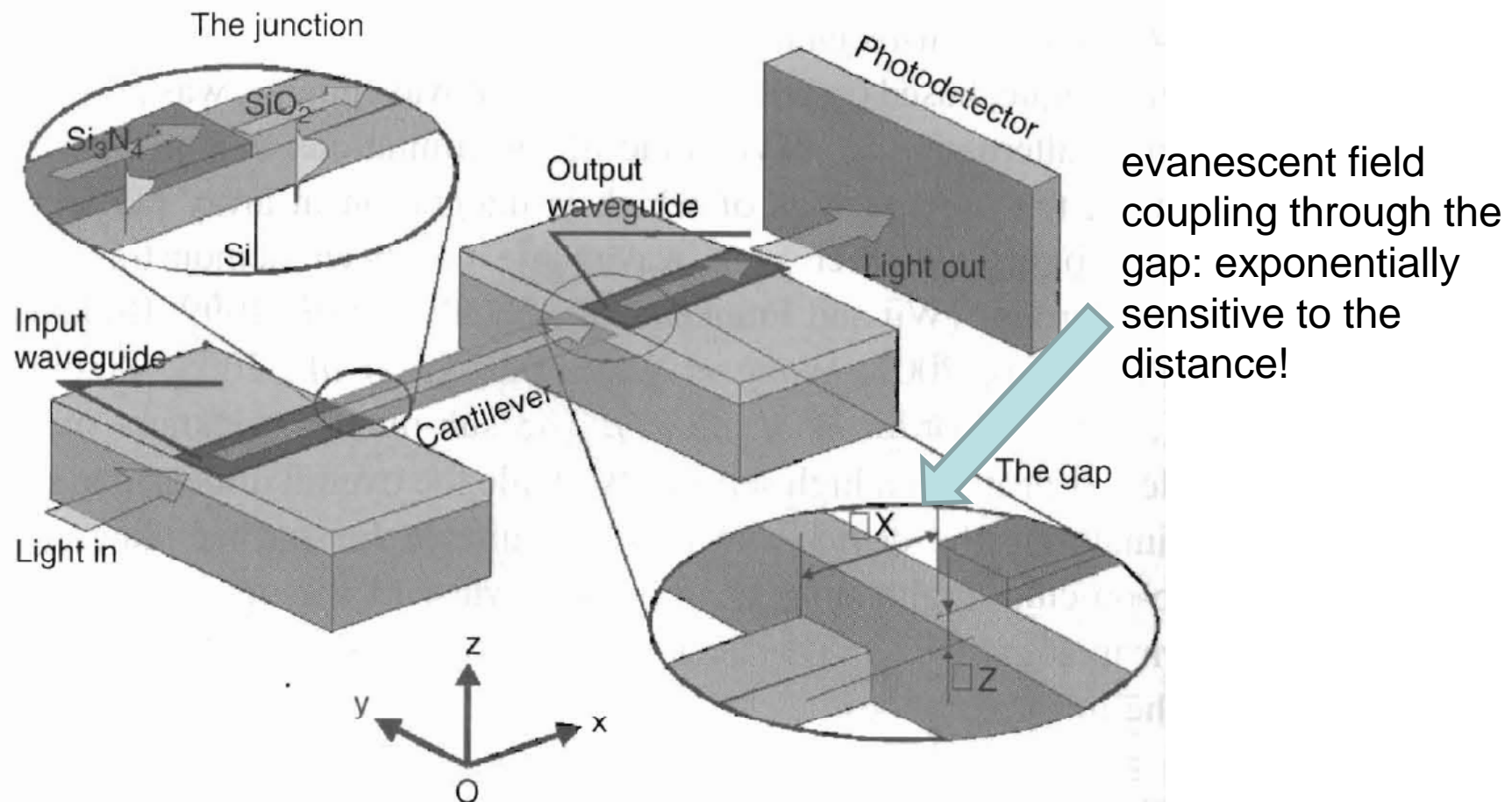
- Optical beam deflection
 - sub-angstrom resolution achievable
 - array measurement (difficult!) achievable using photodetector arrays or scanning laser sources
- Piezoresistivity
- Piezoelectricity
- Interferometry,
- Capacitance

$$\Delta z = \frac{XL}{2D}$$



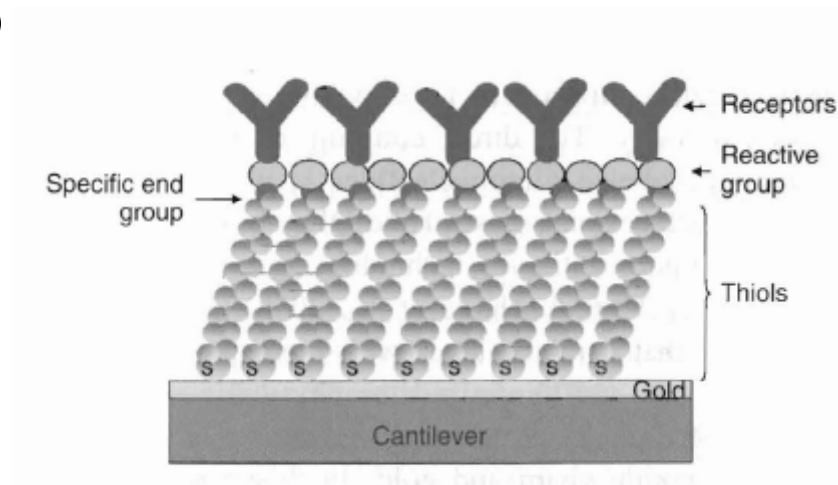
Detection techniques

- Detection via waveguide coupling



Functionalization of Microcantilevers

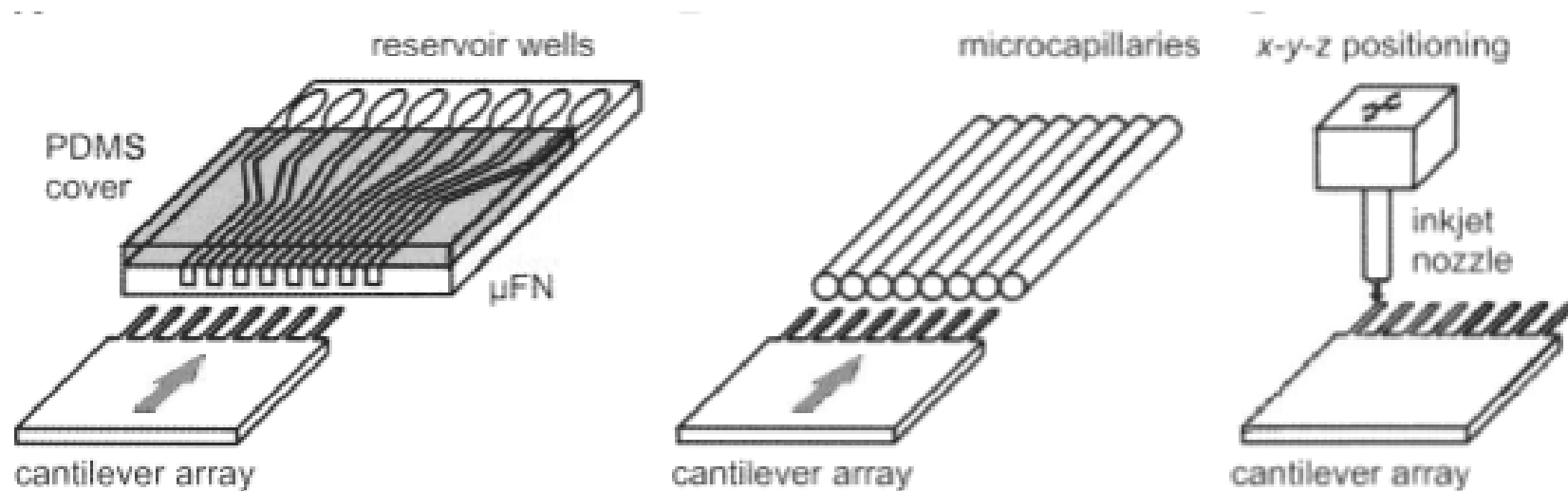
- Mainly based on Au-thiols binding
 - binding of mercapto-acids with subsequent EDC-NHS esterification and binding of a protein via an amino group



- Direct binding of S-terminated DNA molecules
- Binding to silicon via silane chemistry
- Coating with poly-L-lysine, nitrocellulose etc.

Functionalization of Microcantilevers

- Challenging!



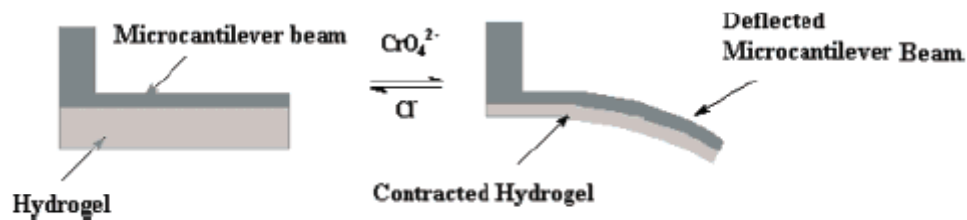
**insertion into
microfluidic channels**

**insertion into
microcapillaries**

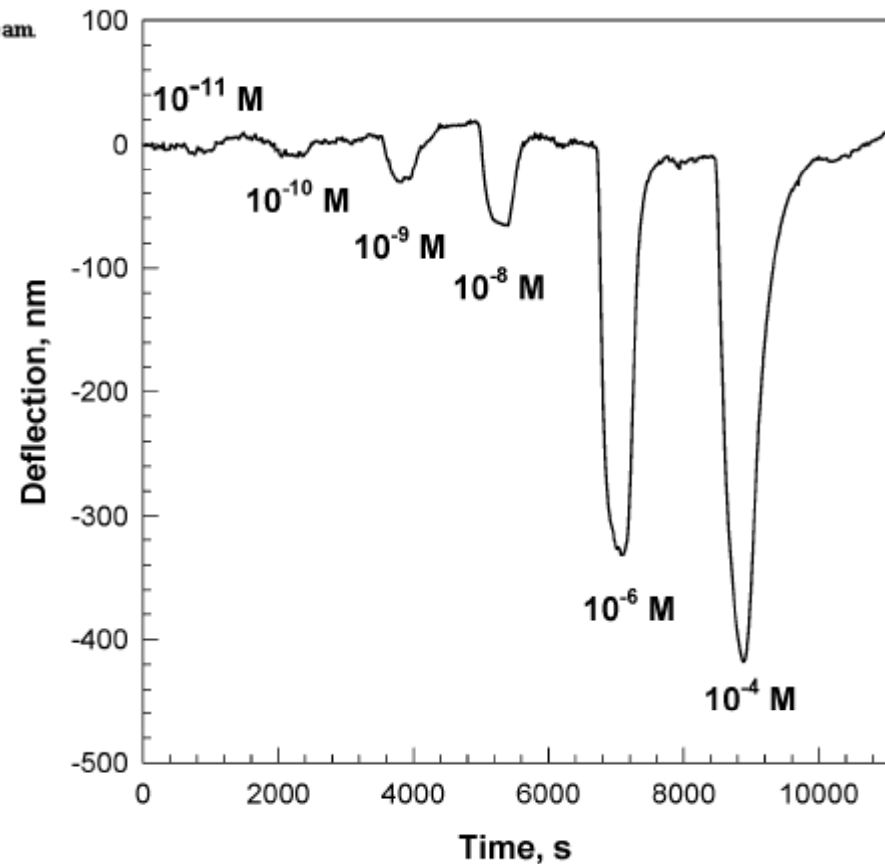
**individual coating
with inkjet dispenser**

Sensing with cantilevers

- static bending detection is very sensitive to the environment (pH, ionic strength). Functionalization allows to detect specific ions

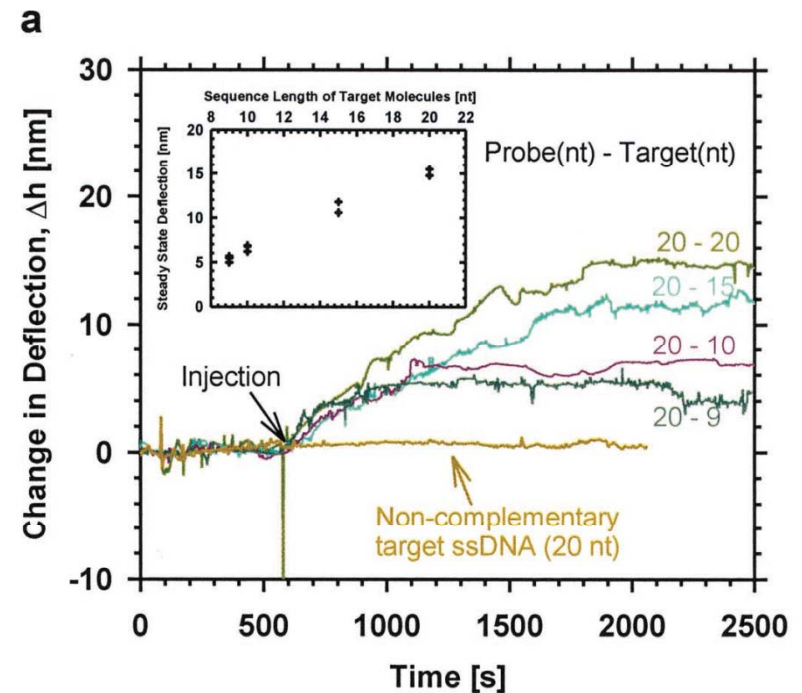
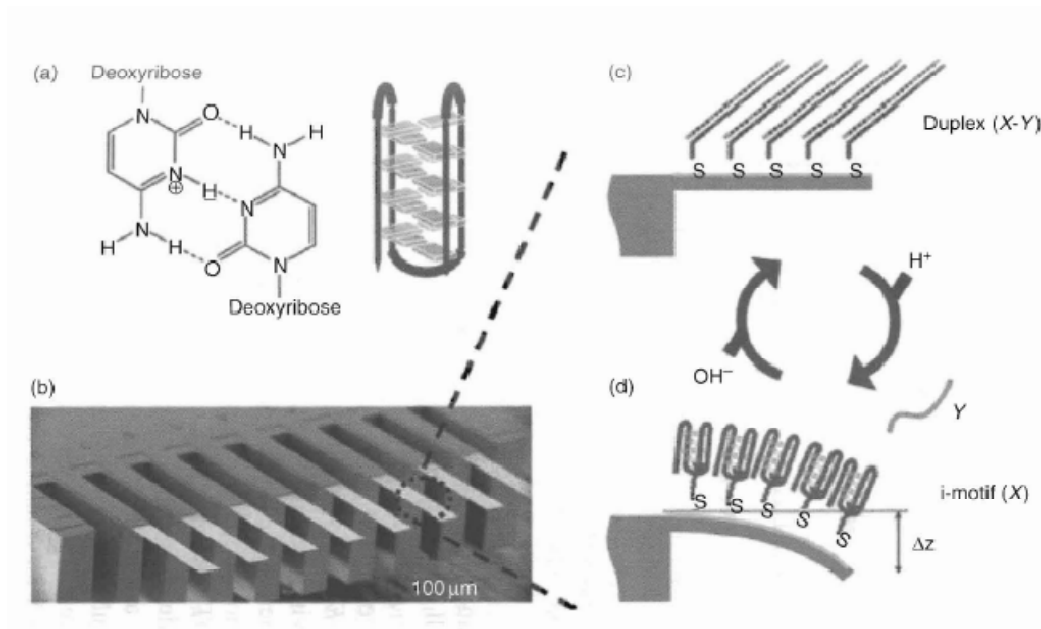


Detection of CrO_4 ions using ATAC ((3-Acrylamidopropyl)-trimethylammonium chloride) hydrogel coated cantilevers



Sensing with cantilevers

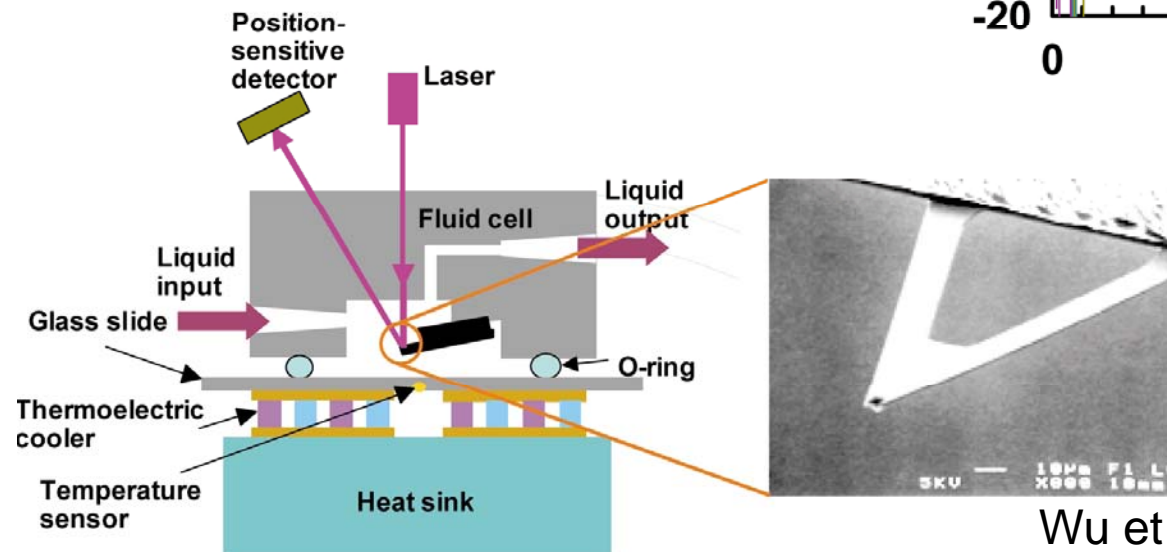
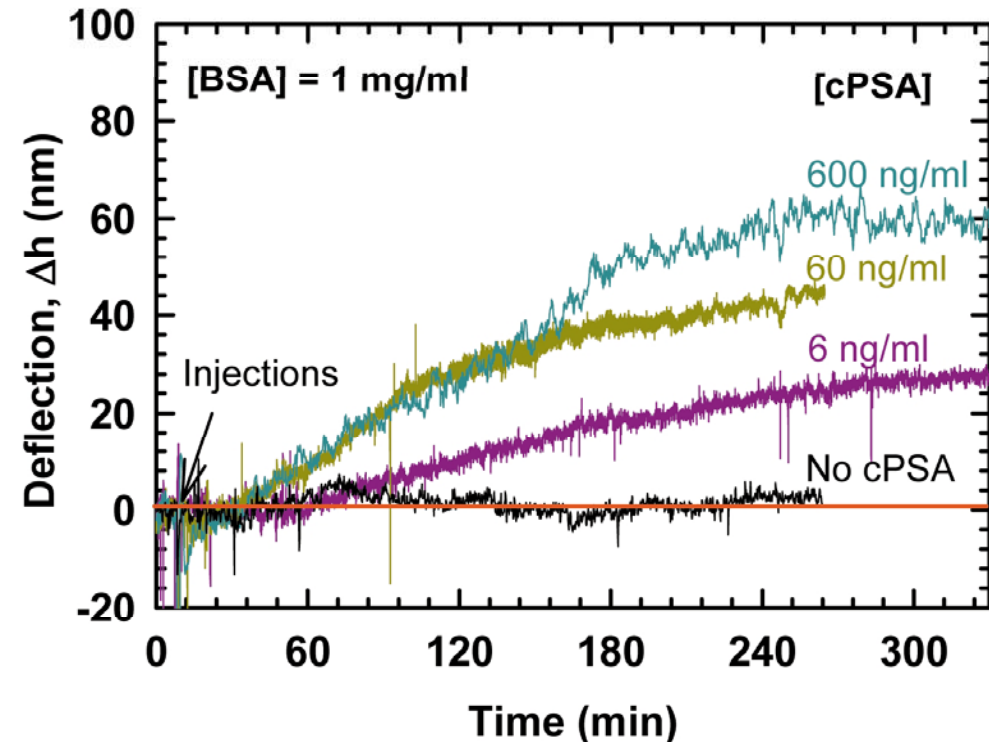
- Genomics:
 - hybridization of DNA (1bp mismatch can be detected)
 - melting temperature
 - conformational changes in DNA



Sensing with cantilevers

- Immunosensing (incl. detecting bacteria and spores)

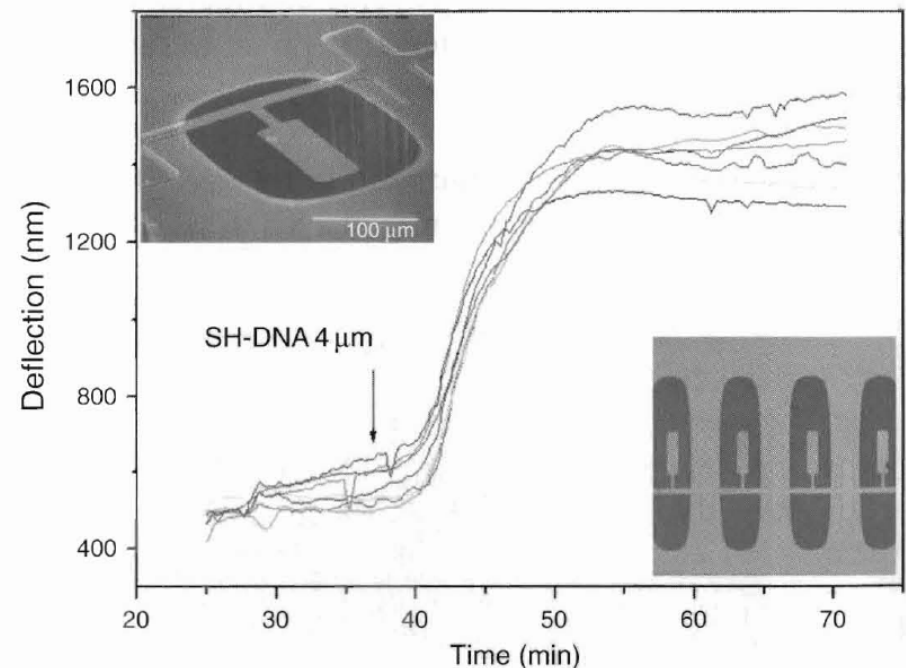
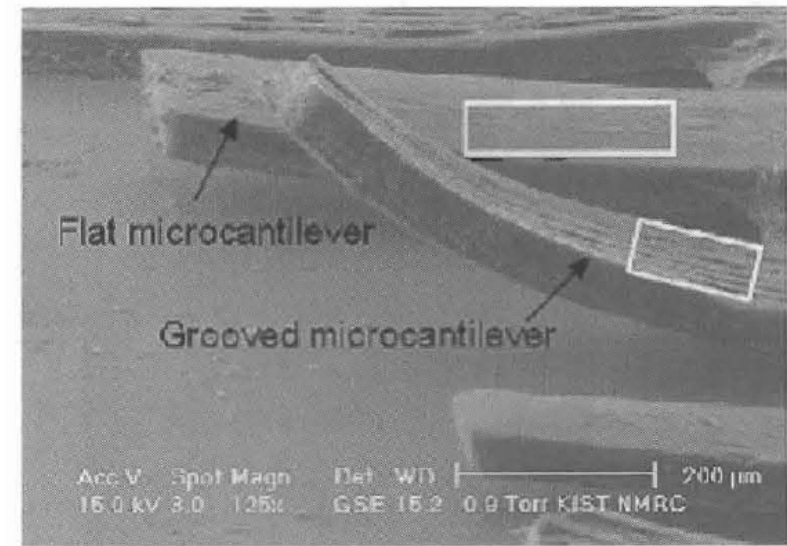
Detection of PSA



Wu et al, Nature Biotech. 19, 856 (2001)

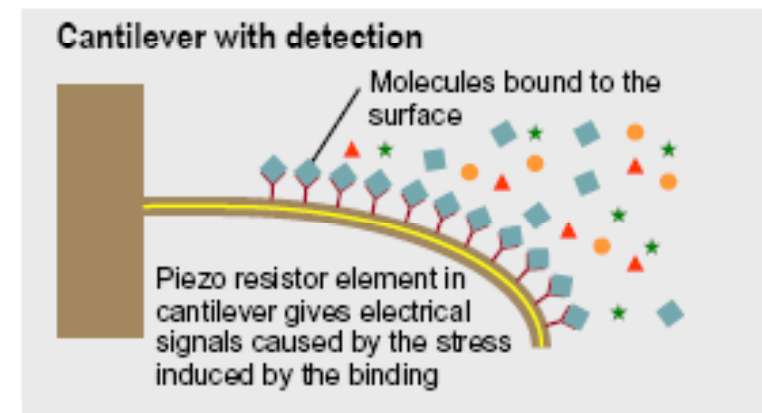
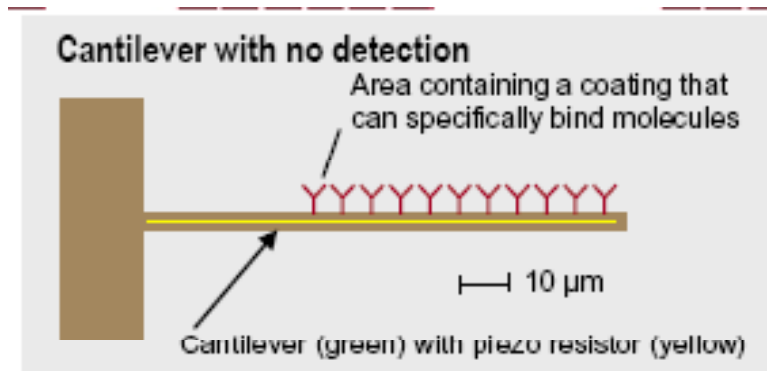
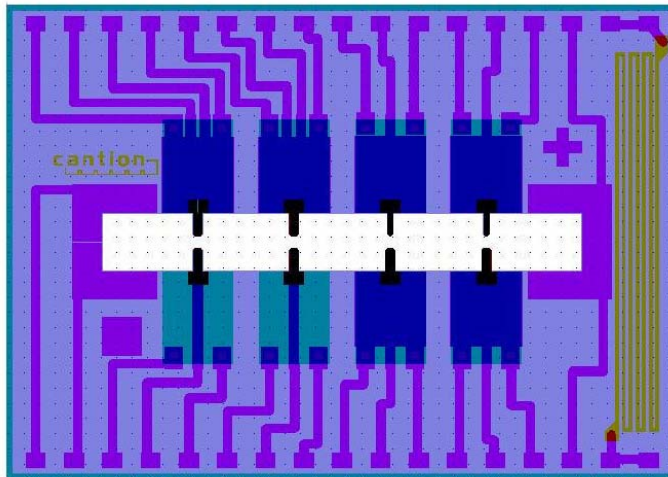
Further development

- Cantilevers with surface nanostructures show better sensitivity
- cantilevers of different geometry
- polymer cantilevers (SU8, PDMS)
- cantilever arrays (lab-on-a-chip)
- cantilever integrated in microfluidic systems



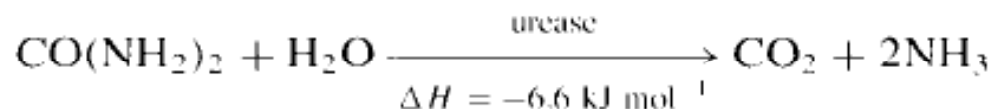
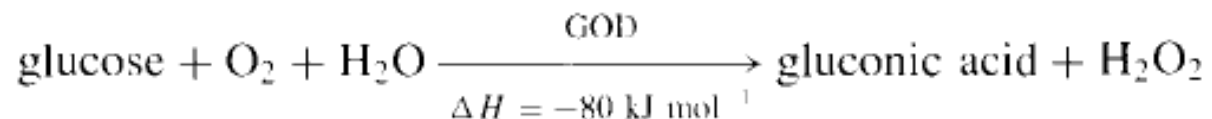
Cantilever-based biosensing

- Canteon technology (NanoNord)
 - Static bending is detected
 - Piezoresistive cantilevers
 - Can be used in referenced mode
 - Placed in a fluidic cartridge

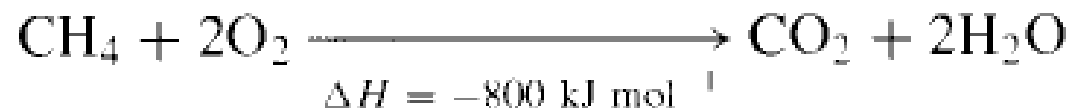


Thermal sensors

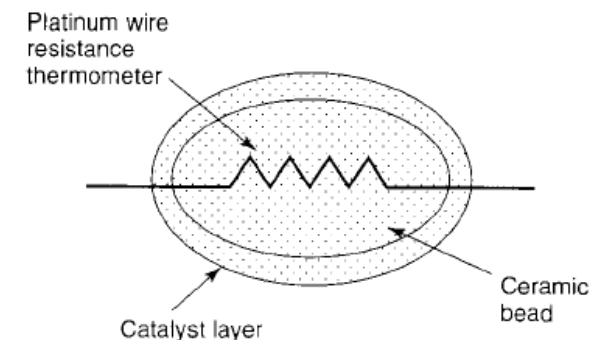
- Thermistors – based on strong change of resistance with temperature – can be used to measure heat production in chemical reactions



Enzyme reaction

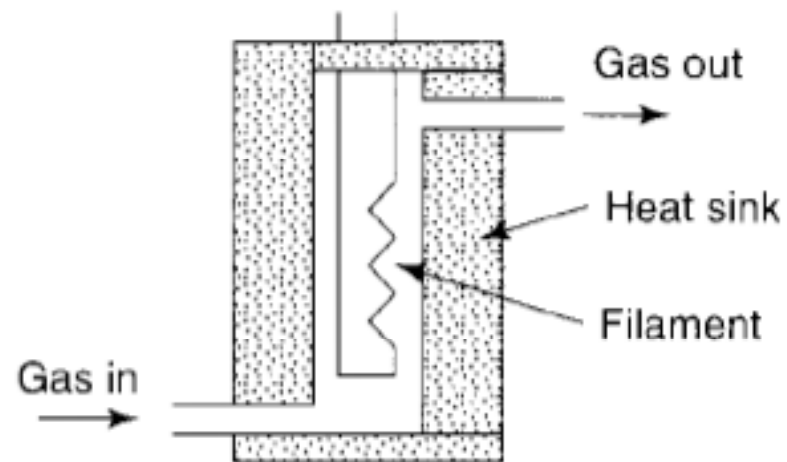


Catalytic gas sensor



Thermal sensors

- Thermal conductivity devices (typically gas chromatography)



Laboratory exercise

Cyclic voltammetry study of ferrocyanide redox reaction.

- Aims:
 - experimentally find electrochemical potential for ferricyanide redox reaction
 - check peak current dependence on concentration and voltage scan rate
 - observe transition from reversible to irreversible behaviour, find α for the reaction (if possible 😊)

Laboratory exercise

- Theory

reversible limit

$$\Delta E_{pp} = 2.218 \frac{RT}{F} \approx 57 \text{ mV (at 298 K)}$$

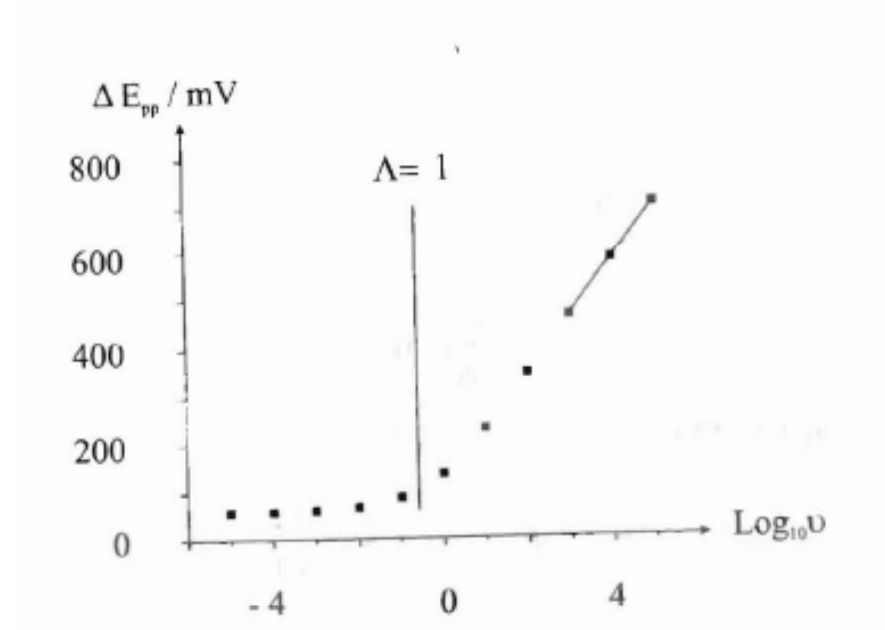
$$I_p = 0.446 FA [C_0] \sqrt{\frac{FDv}{RT}}$$

irreversible limit

$$\Delta E_{pp} \propto \frac{RT}{\alpha F} \ln v; \Delta E_{pp} = \frac{59.4 \text{ mV}}{\alpha F} \log_{10} v + \text{const (at 298 K)}$$

$$I_p = 0.496 \sqrt{\alpha} FA [C_0] \sqrt{\frac{FDv}{RT}}$$

peak-peak distance



reversible limit

irreversible limit

Laboratory exercise

Experiment

- prepare solutions
 - 100mM KCl
 - 100mM $\text{K}_3\text{Fe}(\text{CN})_6$ (stock) and 100mM $\text{K}_4\text{Fe}(\text{CN})_6$ (stock)
- Measurements:
 - Pt film working and counter electrodes, Ag/AgCl reference
 - working concentrations 2mM, 5mM, 10mM, 20mM (at 100 mV/s)
 - scan rates 50mV/s, 100mV/s, 200mV/s, 500mV/s, 1V/s, 2V/s, 5V/s, 10V/s (at 5mM)
- Processing:
 - use diffusion coefficient from Roffel and Graaf article.